

ABSTRACT OF THE DISCLOSURE

An EUV light source having a simple structure which is capable of generating EUV stably with a sufficient intensity and serves as an alternative to a laser plasma light source. The EUV light source comprises an X-ray tube (1) having a primary target, and a secondary target (4) being irradiated with X-rays (2) emitted from the X-ray tube (1). The secondary target (4) generates fluorescence X-rays (5) selected from a group of Be-K α line, Si-L line and Al-L line.